

## Special Issue

# Deep Learning and Machine Learning in Image Processing and Pattern Recognition

### Message from the Guest Editors

Pattern recognition and image processing have grown in importance within the field of artificial intelligence due to the swift advancement of science and technology. This field has developed rapidly in recent years due to the growing use of machine learning and deep learning in image processing and pattern recognition. The goal of this Special Issue is to examine the most recent developments as well as potential directions for machine learning and deep learning in pattern recognition and image processing.

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### Guest Editors

Prof. Dr. Haitao Zhao

Dr. Meng Wang

Prof. Dr. Antonio Fernandez-Caballero

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### Deadline for manuscript submissions

20 October 2025



## Applied Sciences

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### Message from the Editor-in-Chief

As the world of science becomes ever more specialized, researchers may lose themselves in the deep forest of the ever increasing number of subfields being created. This open access journal Applied Sciences has been started to link these subfields, so researchers can cut through the forest and see the surrounding, or quite distant fields and subfields to help develop his/her own research even further with the aid of this multi-dimensional network.

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### Editor-in-Chief

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